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By: h p ~

Date: 1/22/03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Klaus Lowack et al.

Applic. No. : 09/817,963

Filed : March 27, 2001

Title : Method For The Metalization Of An Insulator  
And/Or A Dielectric

Examiner : Brian K. Talbot

Group Art Unit : 1762

A M E N D M E N T under 37 C.F.R. § 1.116

Hon. Commissioner of Patents and Trademarks,  
Washington, D. C. 20231

TECHNOLOGY CENTER 1700

JAN 30 2003

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Sir :

Responsive to the final Office action dated October 22, 2002

kindly amend the above-identified application as follows:

In the Claims:

Claim 4 (amended). A process for metallizing at least one  
insulating layer of an electronic or microelectronic component,  
which comprises:

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